	Application No.	Applicant(s)	
Notice of Allowability	09/620,708	0,708KODAMA ET AL.	
	Examiner	Art Unit	
	John S. Chu	1752	
The MAILING DATE of this communication apperall claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RI of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in this app or other appropriate communication GHTS. This application is subject to	olication. If not included will be mailed in due c	d ourse. THIS
1. This communication is responsive to <u>11/21/03</u> .			
2. The allowed claim(s) is/are 1-25.			
3. The drawings filed on are accepted by the Examine	r.		
 4. Acknowledgment is made of a claim for foreign priority una) All b) Some* c) None of the: 1. Certified copies of the priority documents have 2. Certified copies of the priority documents have 3. Copies of the certified copies of the priority documents have International Bureau (PCT Rule 17.2(a)). * Certified copies not received: Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONM THIS THREE-MONTH PERIOD IS NOT EXTENDABLE. 5. A SUBSTITUTE OATH OR DECLARATION must be subm INFORMAL PATENT APPLICATION (PTO-152) which give 1. CORRECTED DRAWINGS (as "replacement sheets") must 1. Mail of the priority documents including changes required by the Notice of Draftspers 1. Paper No./Mail Date (b) including changes required by the attached Examiner's Paper No./Mail Date Identifying indicia such as the application number (see 37 CFR 1. Including indicia such as the application number (see 37 CFR 1. Including indicia such as the application number (see 37 CFR 1. Including indicia such as the application number (see 37 CFR 1. Including indicia such as the application number (see 37 CFR 1. Including indicia such as the application number (see 37 CFR 1. Including indicia such as the application number (see 37 CFR 1. Including indicia such as the application number (see 37 CFR 1. Including indicia such as the application number (see 37 CFR 1. Including indicia such as the application number (see 37 CFR 1. Including indicia such as the application number (see 37 CFR 1. Including indicia such as the application number (see 37 CFR 1. Including indicia such as the application number (see 37 CFR 1. Including indicia such as the application number (see 37 CFR 1. Including indicia such as the application number (see 37 CFR 1. Including indicia such as the application number (see 37 CFR 1. Including indicia such as the application number (see 37 CFR 1. Including indicia such as the application num	been received. been received in Application No cuments have been received in this research. itted. Note the attached EXAMINER' as reason(s) why the oath or declarates the submitted. it be submitted. it on's Patent Drawing Review (PTO-1). It is Amendment / Comment or in the O	national stage applicational stage applicational stage application of stage application attached	uirements OTICE OF
 each sheet. Replacement sheet(s) should be labeled as such in the such in the sheet. DEPOSIT OF and/or INFORMATION about the deposit attached Examiner's comment regarding REQUIREMENT. 	sit of BIOLOGICAL MATERIAL n	nust be submitted. N	ote the
 Attachment(s) 1. ☑ Notice of References Cited (PTO-892) 2. ☐ Notice of Draftperson's Patent Drawing Review (PTO-948) 3. ☐ Information Disclosure Statements (PTO-1449 or PTO/SB/0 Paper No./Mail Date 4. ☐ Examiner's Comment Regarding Requirement for Deposit of Biological Material 	5. Notice of Informal P 6. Interview Summary Paper No./Mail Dat 7. Examiner's Amendn 8. Examiner's Stateme 9. Other	(PTO-413), e nent/Comment ent of Reasons for Allov John S. Chu	
		Primary Examiner Art Unit: 1752	

Application/Control Number: 09/620,708

Art Unit: 1752

REASONS FOR ALLOWANCE

The following is an examiner's statement of reasons for allowance: The claimed invention is drawn to the following:

- 1 (Amended). A positive photoresist composition comprising:
- (A) a compound capable of generating an acid upon irradiation with actinic rays or radiation and

(B) a resin capable of decomposing under the action of an acid to increase the collability in alkali, containing a repeating unit represented by the following formula (AI):

wherein R represents hydrogen atom, a halogen atom, a substituted or unsubstituted alkyl group having from 1 to 4 carbon atoms, A' represents a single bond and B represents a group represented by formula (I):

$$\begin{pmatrix} R_3 \\ R_2 \end{pmatrix}_m \begin{pmatrix} R_4 \\ R_5 \end{pmatrix}_n$$

$$\begin{pmatrix} R_3 \\ R_6 \end{pmatrix}$$

$$R_7$$

$$(1)$$

wherein R₁ represents hydrogen atom or an alkyl group having from 1 to 4 carbon atoms, which may have a substituent, R₂ to R₇, which may be the same or different, each represents hydrogen atom, an alkyl group which may have a substituent, a cycloalkyl group which may have a substituent or an alkenyl group which may have a substituent, provided that at least one of R₆ and R₇ is not a hydrogen atom and R₆

and R₇ may combine to form a ring, and m and n each independently represents 0 or 1, provided that m and n are not 0 at the same time.

- 9 (Amended). A positive photoresist composition for far ultraviolet exposure, comprising:
- (A) a compound capable of generating an acid upon irradiation with actinic rays or radiation,
- (B) a resin capable of decomposing under the action of an acid to increase the solubility in alkali, containing a repeating unit having a group represented by the following formula (I), and
 - (C) a fluorine-containing and/or silicon-containing surfactant:

$$\begin{pmatrix} R_3 \\ R_2 \end{pmatrix}_m \begin{pmatrix} R_4 \\ R_5 \end{pmatrix}_n$$

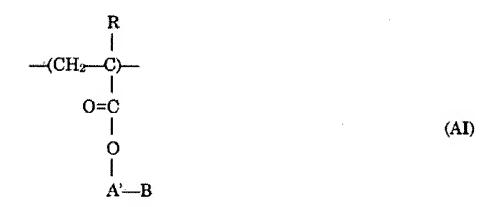
$$\begin{pmatrix} R_3 \\ R_6 \end{pmatrix}_{R_7}$$

$$(1)$$

wherein R₁ represents hydrogen atom or an alkyl group having from 1 to 4 carbon atoms, which may have a substituent, R₂ to R₇, which may be the same or different, each represents hydrogen atom, an alkyl group which may have a substituent, a cycloalkyl group which may have a substituent or an alkenyl group which may have a substituent, provided that at least one of R₆ to R₇ is not a hydrogen atom and R₆

and R₇ may combine to form a ring, and m and n each independently represents 0 or 1, provided that m and n are not 0 at the same time.

- 18 (Amended). A positive photoresist composition for far ultraviolet exposure, comprising:
- (A) a compound capable of generating an acid upon irradiation with actinic rays or radiation,
- (B) a resin capable of decomposing under the action of an acid to increase the solubility in alkali, containing a repeating unit represented by the following formula (AI), and
- (D) a solvent containing the following solvent (a) in an amount of 60% to 90 wt % based on the entire solvent:
- (a) at least one first solvent selected from propylene glycol monomethyl ether acetate, propylene glycol monomethyl ether propionate, methyl 3-methoxypropionate, ethyl 3-methoxypropionate, methyl 3-ethoxypropionate and ethyl 3-ethyoxypropionate;



wherein R represents hydrogen atom, a halogen atom, a substituted or unsubstituted alkyl group having from 1 to 4 carbon atoms, A' represents a single bond and B represents a group represented by formula (I):

$$\begin{pmatrix} R_3 \\ R_2 \end{pmatrix}_m \begin{pmatrix} R_4 \\ R_5 \end{pmatrix}_n$$

$$\begin{pmatrix} R_3 \\ R_6 \end{pmatrix}$$

$$\begin{pmatrix} R_3 \\ R_6 \end{pmatrix}$$

wherein R₁ represents hydrogen atom or an alkyl group having from 1 to 4 carbon atoms, which may have a substituent, R₂ to R₇, which may be the same or different, each represents hydrogen atom, an alkyl group which may be substituent, a cycloalkyl group which may have a substituent or an alkenyl group which may have a substituent, provided that at least one of R₆ and R₇ is not a hydrogen atom and R₆ and R₇ may combine to form a ring, and m and n each independently represents 0 or 1, provided that m and n are not 0 at the same time.

The response of November 21, 2003 contains a Terminal Disclaimer, which overcomes the last outstanding issue for an obviousness-type double patenting rejection over 2002/0006576 A1 to SATO et al.

None of the prior art references of record disclose the claimed invention as recited in claims 1, 9 and 18. The inventive step in claim 1 is to the resin having the formula (AI). Claim 9 recites a resin having a group of formula (I) however also recites the presence of a fluorine-containing and/or silicon-containing surfactant, which is not disclosed in any of the references of record. Claim 18 recites the resin of claim 1 and further recites a least one first solvent as seen

above. Likewise, none of the references of record disclose the claimed invention in claim 18 as recited in the claims above.

Newly cited reference to SATO et al '655 discloses a group Y in claim 1 which meets formula (I) in claim 9, however SATO et al lacks the use of the claimed fluorine-containing and/or silicon-containing surfactants as recited. Further the references fails to disclose the claimed group of formula (AI) in claims 1 and 18.

Because none of the references of record disclose the claimed invention as recited claims 1-25 are seen as allowable and passed to issue.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Examiner Chu whose telephone number is (571) 272-1329. The examiner can normally be reached on Monday - Friday from 9:30 am to 6:00 pm.

The fax phone number for the USPTO is (703) 872-9306.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the Group receptionist whose telephone number is (703) 308-0661.

John S. Chu

Primary Examiner, Group 1700

J.Chu March 3, 2004